



Patent  
Attorney's Docket No. 015290-502

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of	)	
	)	
Helen H. ZHU et al.	)	Group Art Unit: Not Yet Assigned
	)	
Application No.: 09/820,694	)	Examiner: Not Yet Assigned
	)	
Filed: March 30, 2001	)	
	)	
For: METHOD OF PLASMA ETCHING	)	
SILICON NITRIDE	)	

**STATUS INQUIRY**

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

The above application was filed on March 30, 2001 and to date no Official Filing Receipt or Notice to File Missing Parts of Application has been received. Please advise, in writing, as to the current status of the above-captioned application.

Respectfully submitted,

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By: \_\_\_\_\_

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Date: July 12, 2001